

Jun-Bo Yoon

List of Publications by Year in descending order

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195
papers

4,287
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126907

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times ranked

4355
citing authors

#	ARTICLE	IF	CITATIONS
1	Electro-Thermally Actuated Non-Volatile Mechanical Memory With CMOS-Level Operation Voltage and Low Contact Resistance. <i>Journal of Microelectromechanical Systems</i> , 2022, 31, 87-96.	2.5	5
2	Aligned CuO nanowire array for a high performance visible light photodetector. <i>Scientific Reports</i> , 2022, 12, 2284.	3.3	16
3	Wireless and Linear Hydrogen Detection up to 4% with High Sensitivity through Phase-Transition-Inhibited Pd Nanowires. <i>ACS Nano</i> , 2022, 16, 11957-11967.	14.6	13
4	Integration of Gold Nanoparticle-Carbon Nanotube Composite for Enhanced Contact Lifetime of Microelectromechanical Switches with Very Low Contact Resistance. <i>ACS Applied Materials & Interfaces</i> , 2021, 13, 16959-16967.	8.0	5
5	A review of geometric and structural design for reliable flexible electronics. <i>Journal of Micromechanics and Microengineering</i> , 2021, 31, 074001.	2.6	8
6	A Self-Powered Wireless Gas Sensor Node Based on Photovoltaic Energy Harvesting. , 2021, , .		3
7	Utilizing mechanical adhesion force as a high contact force in a MEMS relay. <i>Sensors and Actuators A: Physical</i> , 2021, 331, 112894.	4.1	7
8	Always-On Gas Sensors: Perfectly Aligned, Air-Suspended Nanowire Array Heater and Its Application in an Always-On Gas Sensor (<i>Adv. Funct. Mater.</i> 39/2020). <i>Advanced Functional Materials</i> , 2020, 30, 2070264.	14.9	1
9	Chemo-Mechanically Operating Palladium-Polymer Nanograting Film for a Self-Powered H_2 Gas Sensor. <i>ACS Nano</i> , 2020, 14, 16813-16822.	14.6	40
10	4 W Power MEMS Relay With Extremely Low Contact Resistance: Theoretical Analysis, Design and Demonstration. <i>Journal of Microelectromechanical Systems</i> , 2020, 29, 1304-1313.	2.5	4
11	Perfectly Aligned, Air-Suspended Nanowire Array Heater and Its Application in an Always-On Gas Sensor. <i>Advanced Functional Materials</i> , 2020, 30, 2004448.	14.9	9
12	Geometrically Structured Nanomaterials for Nanosensors, NEMS, and Nanosieves. <i>Advanced Materials</i> , 2020, 32, e1907082.	21.0	26
13	Realization of Nanolene: A Planar Array of Perfectly Aligned, Air-Suspended Nanowires. <i>Small</i> , 2020, 16, e1906845.	10.0	9
14	Ultra-Sensitive Strain Sensor Using High Density Self-Aligned Nano-Cracks. , 2020, , .		3
15	Nanowires: Realization of Nanolene: A Planar Array of Perfectly Aligned, Air-Suspended Nanowires (<i>Small</i> 13/2020). <i>Small</i> , 2020, 16, 2070072.	10.0	0
16	4 W Dual-Contact Material MEMS Relay with a Contact Force Maximizing Structure. , 2020, , .		1
17	Stress-engineered palladium nanowires for wide range (0.1%–3.9%) of H_2 detection with high durability. <i>Nanoscale</i> , 2019, 11, 16317-16326.	5.6	18
18	An investigation of surficial conduction heat loss in perfectly aligned micro-wire array. <i>Applied Physics Letters</i> , 2019, 115, .	3.3	3

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19	Palladium Hydrogen Sensor with Perfectly Aligned and Highly Uniform Nanogap Arrays. , 2019, , .		2
20	Maximizing Percolation Effect using Sub-100 nm Nano-Valley for High Performance Wearable Transparent Pressure Sensor. , 2019, , .		0
21	Gold-Decorated Carbon Nanotube Network as Contact Surface of MEM Switch for Extended Lifetime. , 2019, , .		0
22	Industrial-Grade Fabrication of Nanowire Sensor Device Exploiting Sacrificial Shadow Patterning Method. , 2019, , .		0
23	Self-Powered, Ultra-Reliable Hydrogen Sensor Exploiting Chemomechanical Nano-Transducer and Solar-Cell. , 2019, , .		1
24	High-Performance Copper Oxide Visible-Light Photodetector via Grain-Structure Model. Scientific Reports, 2019, 9, 7334.	3.3	50
25	Integration of a Carbon Nanotube Network on a Microelectromechanical Switch for Ultralong Contact Lifetime. ACS Applied Materials & Interfaces, 2019, 11, 18617-18625.	8.0	11
26	Batch-fabricated CO gas sensor in large-area (8-inch) with sub-10 mW power operation. Sensors and Actuators B: Chemical, 2019, 289, 153-159.	7.8	28
27	Mass-producible structural design and fabrication method for a slim light-guide plate having inverse-trapezoidal light out-couplers. Journal of Micromechanics and Microengineering, 2019, 29, 035001.	2.6	5
28	>1000-Fold Lifetime Extension of a Nickel Electromechanical Contact Device via Graphene. ACS Applied Materials & Interfaces, 2018, 10, 9085-9093.	8.0	23
29	A Low Contact Resistance 4-Terminal Mems Relay: Theoretical Analysis, Design, and Demonstration. Journal of Microelectromechanical Systems, 2018, 27, 497-505.	2.5	7
30	Material-Independent Nanotransfer onto a Flexible Substrate Using Mechanical-Interlocking Structure. ACS Nano, 2018, 12, 4387-4397.	14.6	21
31	First Lateral Contact Probing of 55- μm Fine Pitch Micro-Bumps. Journal of Microelectromechanical Systems, 2018, 27, 1114-1123.	2.5	3
32	A Proactive Plastic Deformation Method for Fine-Tuning of Metal-Based MEMS Devices After Fabrication. Journal of Microelectromechanical Systems, 2018, 27, 1124-1134.	2.5	4
33	Touch Sensors: Industrial Grade, Bending-Insensitive, Transparent Nanoforce Touch Sensor via Enhanced Percolation Effect in a Hierarchical Nanocomposite Film (Adv. Funct. Mater. 42/2018). Advanced Functional Materials, 2018, 28, 1870305.	14.9	0
34	Edge-lit LCD backlight unit for 2D local dimming. Optics Express, 2018, 26, 20802.	3.4	23
35	Industrial Grade, Bending-Insensitive, Transparent Nanoforce Touch Sensor via Enhanced Percolation Effect in a Hierarchical Nanocomposite Film. Advanced Functional Materials, 2018, 28, 1804721.	14.9	50
36	Material-independent nanowire-transfer method based on mechanical interlocking for high performance flexible devices. , 2018, , .		0

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37	Versatile Transfer of an Ultralong and Seamless Nanowire Array Crystallized at High Temperature for Use in High-Performance Flexible Devices. ACS Nano, 2017, 11, 1520-1529.	14.6	48
38	Carbon nanotubes network contact lubrication for highly reliable MEMS switch. , 2017, , .		4
39	Highly aligned suspended nanowire array for self-heating type gas sensors. , 2017, , .		5
40	Inductance enhancement of a MEMS inductor with self-aligned magnetic nanoparticles. , 2017, , .		0
41	Performance-enhanced triboelectric nanogenerator enabled by wafer-scale nanogrates of multistep pattern downscaling. Nano Energy, 2017, 35, 415-423.	16.0	120
42	Realization of large-scale sub-10Ånm nanogratings using a repetitive wet-chemical oxidation and etching technique. Micro and Nano Systems Letters, 2017, 5, .	3.7	5
43	Nanomechanical Encoding Method Using Enhanced Thermal Concentration on a Metallic Nanobridge. ACS Nano, 2017, 11, 7781-7789.	14.6	12
44	Efforts toward ideal microelectromechanical switches. , 2017, , .		1
45	MEMS packaging method without any heating or external force using adhesive bonding assisted by capillary force. , 2017, , .		1
46	Nanotransplantation Printing of Crystallographic-Orientation-Controlled Single-Crystalline Nanowire Arrays on Diverse Surfaces. ACS Nano, 2017, 11, 11642-11652.	14.6	16
47	Linear frequency tuning in an LC-resonant system using a Câ€V response controllable MEMS varactor. Micro and Nano Systems Letters, 2017, 5, .	3.7	0
48	Investigation of the Nanoparticle Electrical Contact Lubrication in MEMS Switches. Journal of Microelectromechanical Systems, 2017, 26, 1417-1427.	2.5	10
49	4-Terminal MEMS relay with an extremely low contact resistance employing a novel one-contact design. , 2017, , .		3
50	High performance flexible tactile sensor array using a large area plastic nano-grating substrate. , 2017, , .		1
51	P-67: Wide Bandwidth Reflective Microshutter Blind Panel for Transparent Organic Light-Emitting Diode Display. Digest of Technical Papers SID International Symposium, 2016, 47, 1389-1391.	0.3	3
52	P-70: Light Shifted Light-guide Plate for Simple Multi-view Spatial/Temporal Hybrid Autostereoscopic Display. Digest of Technical Papers SID International Symposium, 2016, 47, 1399-1401.	0.3	1
53	P-72: Ultra-thin Edge Type Single Sheet Backlight Unit for Seamless Two-dimensional Local Dimming. Digest of Technical Papers SID International Symposium, 2016, 47, 1406-1408.	0.3	5
54	Unconventional Use of a Photoresist as a Nitrogen Gas Generator Forming Transparent Domeâ€Shaped Microcavities. Advanced Engineering Materials, 2016, 18, 559-566.	3.5	2

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55	Stepwise Actuation of an Electrostatic Bimorph Cantilever Actuator Using a Patterned Bottom Electrode. Journal of Microelectromechanical Systems, 2016, 25, 909-915.	2.5	0
56	A Highly Reliable MEMS Relay With Two-Step Spring System and Heat Sink Insulator for High-Power Switching Applications. Journal of Microelectromechanical Systems, 2016, 25, 217-226.	2.5	16
57	Micro and Nanoelectromechanical Contact Switches for Logic, Memory, and Power Applications. KAIST Research Series, 2016, , 65-117.	1.5	2
58	High-Performance Hybrid Complementary Logic Inverter through Monolithic Integration of a MEMS Switch and an Oxide TFT. Small, 2015, 11, 1390-1395.	10.0	12
59	An electrostatic energy harvester exploiting variable-area water electrode by respiration. , 2015, , .		2
60	A surface conductance based fully integrated standard CMOS humidity sensor without post-processing. , 2015, , .		1
61	From microelectromechanical switches to nanoelectromechanical switches: Lessons and differences. , 2015, , .		0
62	Fabrication of a membrane filter with controlled pore shape and its application to cell separation and strong single cell trapping. Journal of Micromechanics and Microengineering, 2015, 25, 105007.	2.6	10
63	Self-cleaning hybrid energy harvester to generate power from raindrop and sunlight. Nano Energy, 2015, 12, 636-645.	16.0	166
64	A Highly Reliable Two-Axis MEMS Relay Demonstrating a Novel Contact Refresh Method. Journal of Microelectromechanical Systems, 2015, 24, 1495-1502.	2.5	15
65	Increasing Capacitance and Self-Resonant Frequency of the MEMS Switched Capacitor Using High- κ TiO_2 and SU-8 Bridged Beam Structure. Journal of Microelectromechanical Systems, 2015, 24, 1006-1015.	2.5	6
66	Highly reliable MEMS relay with two-step spring system and heat sink insulator for power applications. , 2015, , .		5
67	Effect of excitation point on surface phonon fields in phononic crystals in real- and k-space. Journal of Applied Physics, 2015, 117, .	2.5	5
68	A simple breathing rate-sensing method exploiting a temporarily condensed water layer formed on an oxidized surface. Applied Physics Letters, 2015, 106, .	3.3	27
69	Signal Power-Insensitive Analog MEMS Tunable Capacitor by Immobilizing the Movable Plates. Journal of Microelectromechanical Systems, 2015, 24, 1545-1556.	2.5	4
70	Novel buried inverse-trapezoidal micropattern for dual-sided light extracting backlight unit. Optics Express, 2014, 22, 32440.	3.4	4
71	Three-dimensional (3-D) reshaping technique in MEMS devices by solely electrical control with ultrafine tuning resolution. , 2014, , .		3
72	A mechanical and electrical transistor structure (METS) with a sub-2 nm nanogap for effective voltage scaling. Nanoscale, 2014, 6, 7799.	5.6	13

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73	A Complementary Dual-Contact MEMS Switch Using a "Zipping" Technique. Journal of Microelectromechanical Systems, 2014, 23, 710-718.	2.5	24
74	Ultra-low voltage MEMS switch using a folded hinge structure. Micro and Nano Systems Letters, 2014, 2, .	3.7	11
75	Electrostatic micro-actuator with a pre-charged series capacitor: modeling, design, and demonstration. Journal of Micromechanics and Microengineering, 2014, 24, 065012.	2.6	11
76	Photothermal in-situ synthesis of localized tungsten oxide nanobeam structures. , 2014, , .		0
77	Voltage-Controlled $C^{-1}V$ Response Tuning in a Parallel Plate MEMS Variable Capacitor. Journal of Microelectromechanical Systems, 2013, 22, 1403-1413.	2.5	6
78	Complementary Dual-Contact Switch Using Soft and Hard Contact Materials for Achieving Low Contact Resistance and High Reliability Simultaneously. Journal of Microelectromechanical Systems, 2013, 22, 846-854.	2.5	25
79	A new approach to control a deflection of an electroplated microstructure: dual current electroplating methods. Journal of Micromechanics and Microengineering, 2013, 23, 055016.	2.6	8
80	High Throughput Ultralong (20 cm) Nanowire Fabrication Using a Wafer-Scale Nanograting Template. Nano Letters, 2013, 13, 3978-3984.	9.1	38
81	A sub-1-volt nanoelectromechanical switching device. Nature Nanotechnology, 2013, 8, 36-40.	31.5	166
82	Actively transparent display with enhanced legibility based on an organic light-emitting diode and a cholesteric liquid crystal blind panel. Optics Express, 2013, 21, 10358.	3.4	19
83	Improvement of hot switching lifetime in MEMS DC switches using a drain voltage-sustaining capacitor. , 2013, , .		3
84	A newly designed curved beam microshutter display device with high aperture ratio. , 2013, , .		1
85	An ultra-low voltage MEMS switch using stiction-recovery actuation. Journal of Micromechanics and Microengineering, 2013, 23, 045022.	2.6	23
86	Multi-resonant energy harvester exploiting high-mode resonances frequency down-shifted by a flexible body beam. Applied Physics Letters, 2012, 101, .	3.3	18
87	Metal-oxide-semiconductor field effect transistor humidity sensor using surface conductance. Applied Physics Letters, 2012, 100, .	3.3	45
88	Adhesion Force Change by Electrowetting on a Polymer Microlens Array. Journal of Adhesion Science and Technology, 2012, 26, 2079-2086.	2.6	6
89	An Electrostatically Actuated Stacked-Electrode MEMS Relay With a Levering and Torsional Spring for Power Applications. Journal of Microelectromechanical Systems, 2012, 21, 1209-1217.	2.5	32
90	Fabrication of a uniform microlens array over a large area using self-aligned diffuser lithography (SADL). Journal of Micromechanics and Microengineering, 2012, 22, 045002.	2.6	22

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91	An effective light-extracting microstructure for a single-sheet backlight unit for liquid crystal display. <i>Journal of Micromechanics and Microengineering</i> , 2012, 22, 095006.	2.6	11
92	High-performance MEMS relay using a stacked-electrode structure and a levering and torsional spring for power applications. , 2012, , .		3
93	An electrostatic micromechanical biosensor for electrical detection of label-free DNA. <i>Applied Physics Letters</i> , 2012, 100, 163701.	3.3	6
94	CMOS capacitive biosensor with enhanced sensitivity for label-free DNA detection. , 2012, , .		24
95	Use of a Columnar Metal Thin Film as a Nanosieve with Sub-10 nm Pores. <i>Advanced Materials</i> , 2012, 24, 4408-4413.	21.0	22
96	Transparent conducting hybrid thin films fabricated by layer-by-layer assembly of single-wall carbon nanotubes and conducting polymers. <i>Applied Physics A: Materials Science and Processing</i> , 2012, 108, 305-311.	2.3	11
97	A CMOS label-free DNA sensor using electrostatic induction of molecular charges. <i>Biosensors and Bioelectronics</i> , 2012, 31, 343-348.	10.1	26
98	An Extremely Low Contact-Resistance MEMS Relay Using Meshed Drain Structure and Soft Insulating Layer. <i>Journal of Microelectromechanical Systems</i> , 2011, 20, 204-212.	2.5	32
99	Modeling, fabrication and demonstration of a rib-type cantilever switch with an extended gate electrode. <i>Journal of Micromechanics and Microengineering</i> , 2011, 21, 115009.	2.6	10
100	MEMS variable capacitor with superior linearity and large tuning ratio by moving the plate to the increasing-gap direction. , 2011, , .		9
101	Parallel-Plate MEMS Variable Capacitor With Superior Linearity and Large Tuning Ratio Using a Levering Structure. <i>Journal of Microelectromechanical Systems</i> , 2011, 20, 1345-1354.	2.5	30
102	Electrostatic switching biosensor - a novel label-free DNA detection using an electrode charging technique. , 2011, , .		0
103	Fast and robust cantilever switch with suppressed bouncing for ic applications. , 2011, , .		1
104	An insulating liquid environment for reducing adhesion in a microelectromechanical system. <i>Applied Physics Letters</i> , 2011, 99, 113516.	3.3	12
105	Fabrication of a large-scale Ni stamp using a multi-level SU-8 photoresist mold for advanced printed circuit board manufacturing. <i>Journal of Micromechanics and Microengineering</i> , 2011, 21, 065026.	2.6	5
106	Mass-Productible Polydimethylsiloxane (PDMS) Frontlight Unit (FLU) for Reflective Displays. <i>Journal of Display Technology</i> , 2011, 7, 526-531.	1.2	6
107	An autonomous CMOS hysteretic sensor for the detection of desorption-free DNA hybridization. <i>Biosensors and Bioelectronics</i> , 2011, 26, 4591-4595.	10.1	10
108	Liquid-based electrostatic energy harvester with high sensitivity to human physical motion. <i>Smart Materials and Structures</i> , 2011, 20, 125012.	3.5	33

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109	A trans-scaled nanofabrication using 3D diffuser lithography, metal molding and nano-imprinting. Journal of Micromechanics and Microengineering, 2011, 21, 045025.	2.6	9
110	Modeling, fabrication and demonstration of an electrostatic actuator with a coplanar pre-charged electrode. Journal of Micromechanics and Microengineering, 2011, 21, 085012.	2.6	3
111	56.2: A New Reflective-type Transparent Display Using Cholesteric Liquid Crystal. Digest of Technical Papers SID International Symposium, 2010, 41, 838.	0.3	7
112	Simple fabrication of microfluidic channel with nanoporous membrane formed by conventional physical vapor deposition. , 2010, , .		0
113	Optically Selective Microlens Photomasks Using Self-Assembled Smectic Liquid Crystal Defect Arrays. Advanced Materials, 2010, 22, 2416-2420.	21.0	57
114	One-chip electronic detection of DNA hybridization using precision impedance-based CMOS array sensor. Biosensors and Bioelectronics, 2010, 26, 1373-1379.	10.1	43
115	Nanowire Mechanical Switch with a Built-in Diode. Small, 2010, 6, 1197-1200.	10.0	20
116	Exchangeable self-curable liquid gate dielectric embedded field effect transistor. Applied Physics Letters, 2010, 97, .	3.3	3
117	Annealing effect on contact characteristics in TiN based 3-terminal NEM relays. , 2010, , .		0
118	Use of nanoporous columnar thin film in the wafer-level packaging of MEMS devices. Journal of Micromechanics and Microengineering, 2010, 20, 045002.	2.6	10
119	High performance microshutter device with space-division modulation. Journal of Micromechanics and Microengineering, 2010, 20, 075030.	2.6	10
120	Analytical Modeling and Thermodynamic Analysis of Robust Superhydrophobic Surfaces with Inverse-Trapezoidal Microstructures. Langmuir, 2010, 26, 17389-17397.	3.5	33
121	A robust superhydrophobic and superoleophobic surface with inverse-trapezoidal microstructures on a large transparent flexible substrate. Soft Matter, 2010, 6, 1401.	2.7	319
122	Electrowetting on a Polymer Microlens Array. Langmuir, 2010, 26, 12443-12447.	3.5	36
123	Maneuvering actuation voltage of a electrostatic MEMS switch with a new coplanar pre-charged electrode. , 2010, , .		1
124	Study of a new spring structure for a mechanically reliable micromirror. , 2010, , .		0
125	Mechanical Reliability of a Digital Micromirror With Interdigitated Cantilevers. Journal of Microelectromechanical Systems, 2010, 19, 1197-1206.	2.5	6
126	Novel voltage controlled spatial modulation method for digital microshutter display with high performance. , 2009, , .		0

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127	Densely-Packed Microbowl Array with Balanced Dielectrophoretic Forces for Single-Cell Microarray. Materials Research Society Symposia Proceedings, 2009, 1222, 1.	0.1	0
128	Spontaneous Lamellar Alignment in Thickness-Modulated Block Copolymer Films. Advanced Functional Materials, 2009, 19, 2584-2591.	14.9	63
129	Lock-and-Key-Geometry Effect of Patterned Surfaces: Wettability and Switching of Adhesive Force. Small, 2009, 5, 90-94.	10.0	104
130	Modeling, Design, Fabrication, and Demonstration of a Digital Micromirror With Interdigitated Cantilevers. Journal of Microelectromechanical Systems, 2009, 18, 1382-1395.	2.5	13
131	MEMS-Based Tunable LC Bandstop Filter With an Ultra-Wide Continuous Tuning Range. IEEE Microwave and Wireless Components Letters, 2009, 19, 710-712.	3.2	27
132	Linearly variable inductor with RF MEMS switches to enlarge a continuous tuning range. , 2009, , .		4
133	A conventional route to scalable morphology-controlled regular structures and their superhydrophobic/hydrophilic properties for biochips application. Lab on A Chip, 2009, 9, 2140.	6.0	33
134	3-terminal nanoelectromechanical switching device in insulating liquid media for low voltage operation and reliability improvement. , 2009, , .		31
135	Indium Tin Oxide (ITO) Transparent MEMS Switches. , 2009, , .		6
136	A Highly Flexible Superhydrophobic Microlens Array with Small Contact Angle Hysteresis for Droplet-Based Microfluidics. , 2009, , .		2
137	Nanoelectromechanical (NEM) relays integrated with CMOS SRAM for improved stability and low leakage. , 2009, , .		58
138	A One-Step Route to a Perfectly Ordered Wafer-Scale Microbowl Array for Size-Dependent Superhydrophobicity. Small, 2008, 4, 211-216.	10.0	37
139	NEMS switch with 30nm-thick beam and 20nm-thick air-gap for high density non-volatile memory applications. Solid-State Electronics, 2008, 52, 1578-1583.	1.4	94
140	Mechanically Operated Random Access Memory (MORAM) Based on an Electrostatic Microswitch for Nonvolatile Memory Applications. IEEE Transactions on Electron Devices, 2008, 55, 2785-2789.	3.0	21
141	High-Q, tunable-gap MEMS variable capacitor actuated with an electrically floating plate. , 2008, , .		10
142	Silicon Photonic Wire Filter Using Asymmetric Sidewall Long-Period Waveguide Grating in a Two-Mode Waveguide. IEEE Photonics Technology Letters, 2008, 20, 520-522.	2.5	19
143	Design and fabrication of a micropatterned polydimethylsiloxane (PDMS) light-guide plate for sheetless LCD backlight unit. Journal of the Society for Information Display, 2008, 16, 329-335.	2.1	11
144	Fabrication and characterization of a nanoelectromechanical switch with 15-nm-thick suspension air gap. Applied Physics Letters, 2008, 92, .	3.3	130

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145	A simple and effective fabrication method for various 3D microstructures: backside 3D diffuser lithography. <i>Journal of Micromechanics and Microengineering</i> , 2008, 18, 125015.	2.6	52
146	A new method of driving an AMOLED with MEMS switches. <i>Proceedings of the IEEE International Conference on Micro Electro Mechanical Systems (MEMS)</i> , 2008, , .	0.0	1
147	3.4: Invited Paper: A Novel Use of MEMS Switches in Driving AMOLED. <i>Digest of Technical Papers SID International Symposium</i> , 2008, 39, 13.	0.3	1
148	A Dram-Like Mechanical Non-Volatile Memory. , 2007, , .		7
149	PI: A Novel LCD Backlight Unit using a Light&#guide Plate with High Fill&#factor Microlens Array and a Conical Microlens Array Sheet. <i>Digest of Technical Papers SID International Symposium</i> , 2007, 38, 465-468.	0.3	6
150	Simple liquid crystal display backlight unit comprising only a single-sheet micropatterned polydimethylsiloxane (PDMS) light-guide plate. <i>Optics Letters</i> , 2007, 32, 2665.	3.3	67
151	MEMS Variable Capacitor Actuated with an Electrically Floating Plate. , 2007, , .		8
152	Sloping profile and pattern transfer to silicon by shape-controllable 3-D lithography and ICP. <i>Sensors and Actuators A: Physical</i> , 2007, 139, 281-286.	4.1	6
153	A 3-D planar microlens for an effective monolithic optical interconnection system. <i>IEEE Photonics Technology Letters</i> , 2006, 18, 814-816.	2.5	11
154	Microlens array diffuser for a light-emitting diode backlight system. <i>Optics Letters</i> , 2006, 31, 3016.	3.3	147
155	Fabrication of three-dimensional SiC-based ceramic micropatterns using a sequential micromolding-and-pyrolysis process. <i>Microelectronic Engineering</i> , 2006, 83, 2475-2481.	2.4	12
156	High Fill-Factor Paraboloidal Microlens Arrays. , 2006, , .		1
157	Self-assembled monolayer-assisted thin metal polishing for fabricating uniform 3D microstructures. <i>Journal of Micromechanics and Microengineering</i> , 2005, 15, 1027-1032.	2.6	1
158	A high efficiency 3D planar microlens for monolithic optical interconnection system. , 2005, , .		0
159	Micromachined CPW-fed suspended patch antenna for 77 GHz automotive radar applications. , 2005, , .		3
160	A simple and effective lift-off with positive photoresist. <i>Journal of Micromechanics and Microengineering</i> , 2005, 15, 2136-2140.	2.6	65
161	60-GHz CPW-fed post-supported patch antenna using micromachining technology. <i>IEEE Microwave and Wireless Components Letters</i> , 2005, 15, 635-637.	3.2	75
162	Experimental Analysis of the Effect of Metal Thickness on the Quality Factor in Integrated Spiral Inductors for RF ICs. <i>IEEE Electron Device Letters</i> , 2004, 25, 76-79.	3.9	57

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163	Shape-controlled, high fill-factor microlens arrays fabricated by a 3D diffuser lithography and plastic replication method. <i>Optics Express</i> , 2004, 12, 6366.	3.4	93
164	3-D construction of monolithic passive components for RF and microwave ICs using thick-metal surface micromachining technology. <i>IEEE Transactions on Microwave Theory and Techniques</i> , 2003, 51, 279-288.	4.6	88
165	CMOS-compatible surface-micromachined suspended-spiral inductors for multi-GHz silicon RF ICs. <i>IEEE Electron Device Letters</i> , 2002, 23, 591-593.	3.9	123
166	A new monolithic microbiosensor for whole blood analysis. <i>Sensors and Actuators A: Physical</i> , 2002, 95, 108-113.	4.1	11
167	Fabrication of polymeric large-core waveguides for optical interconnects using a rubber molding process. <i>IEEE Photonics Technology Letters</i> , 2000, 12, 62-64.	2.5	44
168	A high fill-factor infrared bolometer using micromachined multilevel electrothermal structures. <i>IEEE Transactions on Electron Devices</i> , 1999, 46, 1489-1491.	3.0	46
169	Monolithic integration of 3-D electroplated microstructures with unlimited number of levels using planarization with a sacrificial metallic mold (PSMM). , 1999, , .		10
170	A thermal inkjet printhead with a monolithically fabricated nozzle plate and self-aligned ink feed hole. <i>Journal of Microelectromechanical Systems</i> , 1999, 8, 229-236.	2.5	48
171	Surface micromachined solenoid on-Si and on-glass inductors for RF applications. <i>IEEE Electron Device Letters</i> , 1999, 20, 487-489.	3.9	107
172	Monolithic Fabrication of Electroplated Solenoid Inductors Using Three-Dimensional Photolithography of a Thick Photoresist. <i>Japanese Journal of Applied Physics</i> , 1998, 37, 7081-7085.	1.5	39
173	Hermetically Sealed Inductor-Capacitor (LC) Resonator for Remote Pressure Monitoring. <i>Japanese Journal of Applied Physics</i> , 1998, 37, 7124-7128.	1.5	80
174	Multilevel microstructure fabrication using single-step 3D photolithography and single-step electroplating. , 1998, , .		16
175	A New Monolithic Inkjet Printhead Using Single Crystalline Silicon For A Heating Resistor. , 1998, , .		1
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